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of

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Application Number	10/757,030
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Filing Date	January 13, 2004
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First Named Inventor	Xie, Jun
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Art Unit

Examiner Name

Attorney Docket Number	020859-002610US
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[illegible][illegible]

**Examiner
Signature**

Date Considered

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60238010 v1



PTO/SB/08B (08-03)

INFORMATION DISCLOSURE STATEMENT BY APPLICANT (use as many sheets as necessary)		Complete if Known			
		Application Number	10/757,030		
		Filing Date	January 13, 2004		
		First Named Inventor	Xie, Jun		
		Art Unit	3754 3281		
		Examiner Name	Unassigned <i>Boydman</i>		
Sheet	1	of	1	Attorney Docket Number	020859-002610US

NON PATENT LITERATURE DOCUMENTS			
Examiner Initials *	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T ²
<i>J</i>	1	DUBOIS et al., Electrostatically Actuated Gas Microvalve Based on a Ta-Si-N Membrane, 14th IEEE International Conference on Micro Electro Mechanical Systems, 2001, pp. 535-538.	
<i>J</i>	2	KOVACS, G.T.A., Micro Machined Transducers Sourcebook, McGraw-Hill, 1998, pp. 819-838, and 883-899.	
<i>J</i>	3	WIJNGAART et al., A High-Storke, High-Pressure Electrostatic Actuator for Valve Applications, Sensors and Actuators, A 100 (2002), pp 264-271.	
<i>J</i>	4	WU et al., MEMS Flow Sensors for Nano-Fluidic Applications, Sensors and Actuators A: Physical, 89 (1-2) (2001) pp 152-158.	
<i>J</i>	5	YAO et al., Dielectric Charging Effects on Parylene Electrostatic Actuators, IEEE, 2002, pp 614-617.	
<i>J</i>	6	YANG et al., Surface Micromachined Leakage Proof Parylene Check Valve, the 14th IEEE International Conference on Micro Electro Mechanical Systems (MEMS'01), Interlaken, Switzerland, 2001, pp 539-542.	

Examiner Signature	<i>[Signature]</i>	Date Considered	<i>7/22/03</i>
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